Preliminary communication

X-ray crystal structure of the dimethylgallium azide polymer and its use as a gallium nitride precursor *

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Abstract

An X-ray diffraction study reveals that dimethylgallium azide (1) exists as a polymer in the solid state. The basic repeating unit, Me_2GaN_3 , forms a spiral along the *a*-axis of an orthohombic unit cell. Compound 1 serves as a gallium nitride precursor.

Although several Group 13 dialkyl azides have been known for some time, relatively little structural information in the solid state is available for these compounds [1,2]. Dimethylgallium azide, for example, was prepared via the reaction of Me₃Ga with HN₃, ClN₃, or Me₃GeN₃. The trimeric formulation, [Me₂GaN₃]₃, involving a six-membered Ga₃N₃ ring, was based on cryoscopic molecular weight data as well as vibrational spectroscopic data. We have prepared dimethylgallium azide by treatment of Me₂GaCl with NaN₃ **. Interestingly, this compound is polymeric in the solid state.

Crystal data: $[C_2H_6GaN_3]_{\infty}$, M = 141.83 (monomer), orthohombic, space group $P2_12_12_1$, a 5.217(8), b 8.452(2), c 12.690(2) Å, U 559.6 Å³, D_c 1.690 g cm⁻³, Z = 4,

^{*} This manuscript is dedicated to Professor F.G.A. Stone, F.R.S., on the occasion of his 65th birthday and in recognition of his many seminal contributions to organometallic chemistry.

^{**} Dimethylgallium chloride was prepared in situ by the slow addition of two equivalents of MeLi to one equivalent of GaCl₃ in toluene solution at -78°C. The Me₂GaCl solution was then added to one equivalent of NaN₃ in toluene at -78°C. The stirred reaction mixture was allowed to warm to room temperature, following which it was heated under reflux for eighteen hours. After removal of the solvent under vacuum the white residue was purified by sublimation (58°C at 10⁻³ Torr). The yield of colorless crystalline [Me₂GaN₃]_∞ was >95%. M.P. 58-59°C (lit. 64°[1]); I.R. 2175 s br (r(N≡N)) cm⁻¹; ¹H NMR (PhMe-d₈, 300 MHz, 25°C, rel. Me₄Si (δ 0.0)), δ 0.720 s Ga-CH₃; mass spec. (E.I. 70 eV), highest peak observed at m/e = 412 ([Me₂GaN₃]₃-CH₃).



Fig. 1. Structure of polymeric dimethylgallium azide (1). Important bond lengths and angles: Ga-N(1) 2.039(6), Ga-N(1)' 2.051(6), N(1)-N(2), 1.201(9), N(2)-N(3) 1.121(9), Ga-C(1) 1.924(8), Ga-C92) 1.947(8) Å, Ga-N(1)-N(2) 115.2(5), N(1)-N(2)-N(3) 179.3(9), N(1)-Ga-N(1)' 98.6(2), Ga-N(1)-Ga' 131.5 (1)°, N(1)-Ga-C(1) 106.3(3), N(1)-Ga-C(2) 103.4(3), C(1)-Ga-C(2) 132.5(4)°.

 $\lambda(\text{Mo-}K_{\alpha}) = 0.71073$ Å, $\mu(\text{Mo-}K_{\alpha})$ 47.85 cm⁻¹. A total of 1987 reflections was collected on an Enraf-Nonius CAD 4 diffractometer at $23 \pm 2^{\circ}$ using the $\theta/2\theta$ scan mode. The data were corrected for Lorentz, polarization, decay, and absorption. The structure was solved by Patterson methods and refined (full-matrix least-squares) using 906 reflections with $I > 6.0\sigma(I)$. The final R and R_w values were 0.0394 and 0.0428, respectively.

The basic repeating unit, Me₂GaN₃ (Fig. 1), forms a spiral along the *a*-axis of the orthorhombic unit cell. The gallium atoms in the chain (Ga, Ga') are bridged by a single nitrogen (N(1)) of the azide group. Within experimental error, the distances are equal along the Ga-N chain (2.039(6) and 2.051(6) Å) and the bond angles at Ga and N are 98.6(2)° and 131.5(1)°, respectively. Within each azide group there are two distinct N-N bond distances: 1.201(9) and 1.121(9) Å for N(1)-N(2) and N(2)-N(3), respectively. As in the case of the dialuminum azide anion $[Al_2(CH_3)_6N_3]^-$ [3], the longer distance corresponds to the bond between the middle nitrogen and the nitrogen bonded to the metal. The geometries at nitrogen and gallium are trigonal planar and tetrahedral, respectively. However, there is a wide variation of angles at gallium and the C-Ga-C angle is surprisingly large (132.5(4)°).

We have found that 1 is an excellent precursor for the growth of GaN under relatively mild conditions [4]. Film growth was achieved in a cold-wall reactor at a substrate temperature of 400 °C and a helium carrier gas pressure of 10 Torr. The substrate was Si(100). The deposited film was identified as GaN by the presence of N(2s) and Ga(3d) XPS peaks at 397.2 and 19.7 eV, respectively. However, it was difficult to establish the stoichiometry exactly because of preferential elimination of nitrogen during sputtering. The GaN was shown to be polycrystalline by X-ray powder diffraction.

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